

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (substitute form 1449A)	Application Number: 09/810,828
	Filing Date: 03/16/2001
	First Named Inventor: ZARRABIAN
	Group Art Unit: 2881
Sheet 1 of 1	Examiner Name: unassigned

U.S. Patent Documents

Examiner Initials	Cite No.	Document No.	Name of Applicant	Date	Class	Sub-class	Filing Date (if appropriate)
JRA	1	6,057,925	Anthon	05/02/00	356	419	
	2	6,002,479	Barwicz et al.	12/14/99	356	326	
	3	5,991,023	Morawski et al.	11/23/99	356	326	
	4	5,850,292	Braun	12/15/98	356	419	
	5	5,760,910	Lepper, Jr. et al.	06/02/98	356	416	
	6	5,719,989	Cushing	01/17/98	359	589	
	7	5,583,683	Scobey	12/10/96	359	127	
	8	5,303,165	Ganz et al.	04/12/94	364	571.01	
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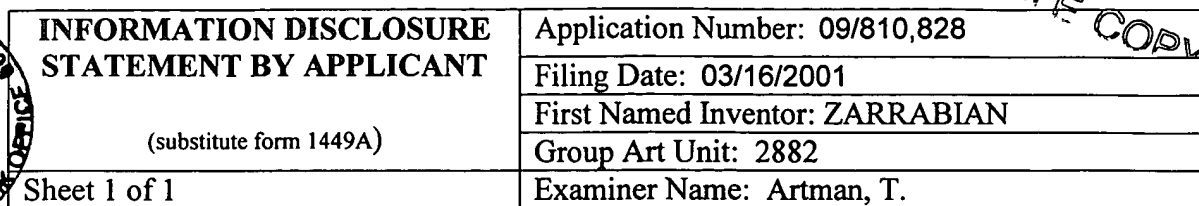
FOREIGN PATENT DOCUMENTS

		Office	Number	Class	Name of Applicant (1 st inventor)	Date of Publication	English Translation

OTHER ART

	14	Haruo Takashasi, <u>Temperature Stability of Thin-Film Narrow-Bandpass Filters Produced by Ion-Assisted Deposition</u> , APPLIED OPTICS, Vol. 34, No. 4, 667-75 (February 1, 1995)
EXAMINER		DATE CONSIDERED 1/22/03

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		Office	Number	Class	Name of Applicant (1 st inventor)	Date of Publication	English Translation
<i>JRA</i>	4	EP	0 442 738 A2	G02B 5/28	Vincent	08/21/91	Eng. doc.
<i>JRA</i>	5	WO	95/20144	G01J/ 9/02	Pratt	07/27/95	Eng. Doc.

EXAMINER *[Signature]* DATE CONSIDERED 6/30/03